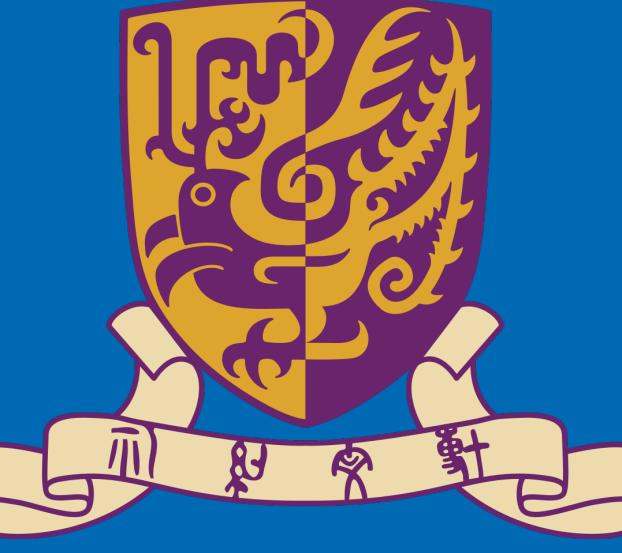


DeePattern: Layout Pattern Generation with Transforming Convolutional Auto-Encoder



cadence

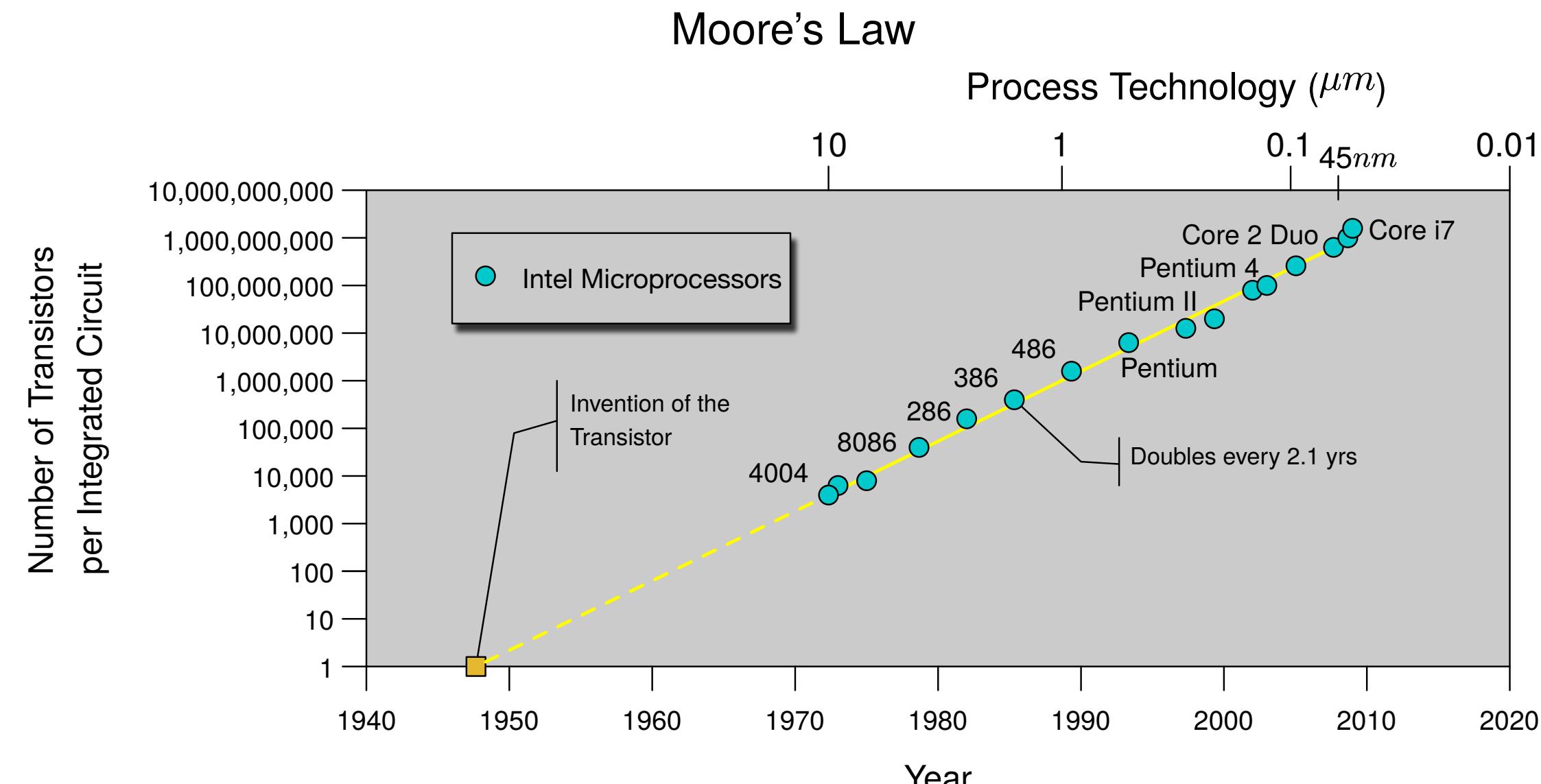
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Backgrounds

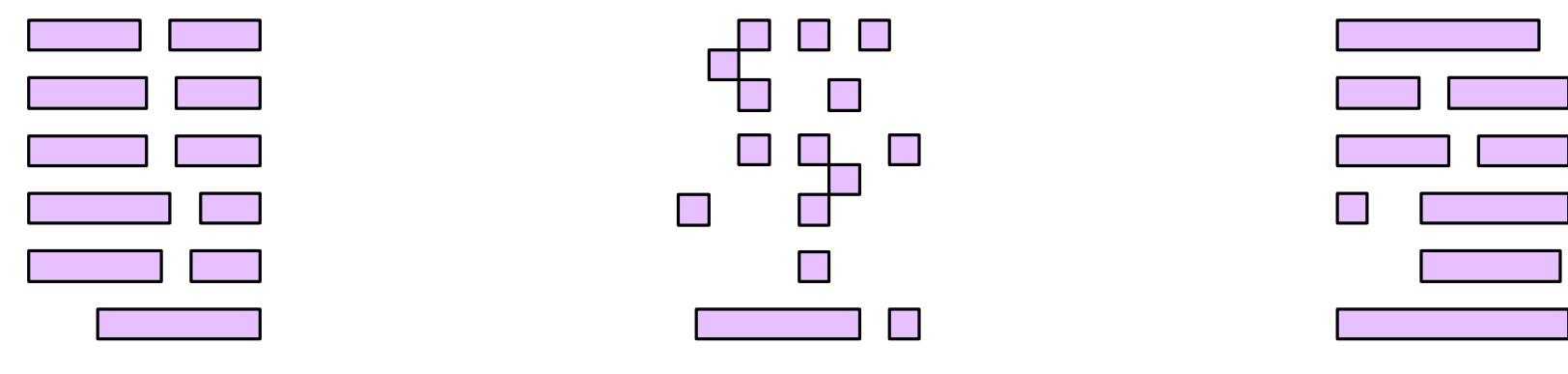
Moore's Law to Extreme Scaling



EUV Brings Challenges in DFM

- ▶ Hotspot detection and fix
- ▶ Previous researches show the significance of a diverse and balanced training data set. [Yang+, SPIE'17]
- ▶ Hotspot pattern library covering the design space required by machine learning and pattern matching solutions.
- ▶ Lithographic simulation challenge due to complicated computational lithography model under EUV nodes. [Levinson+, SPIE'18]
- ▶ Early technology node development
 - ▶ Due to long logic to layout cycle, test layout patterns are not usually available.
 - ▶ OPC convergence problem.
 - ▶ Patterns are required to massage Design rule, OPC recipe, ...

Related Works on Pattern Generation

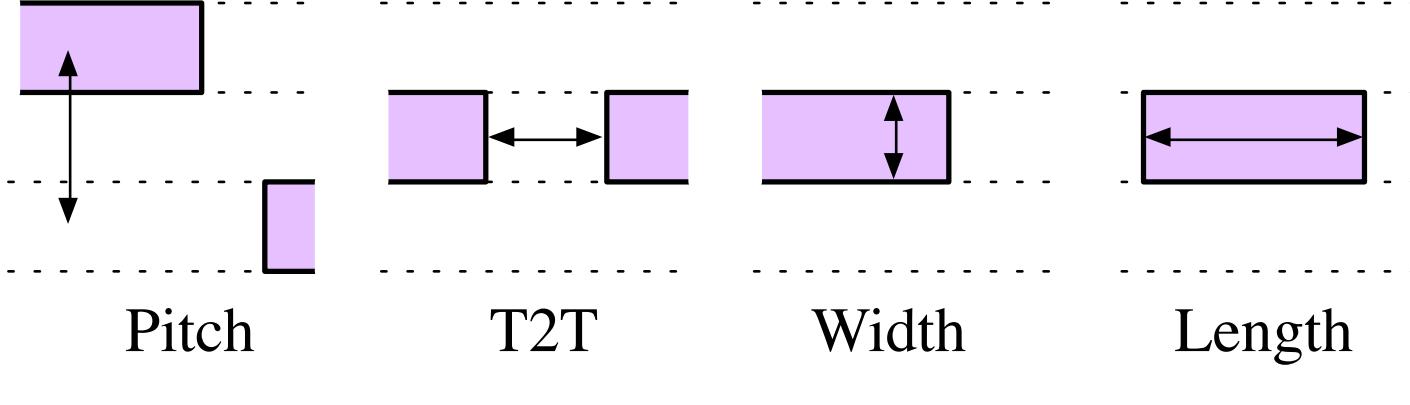


- ▶ Transferring from previous technology node. (not applicable for large technology node gap) [Zhuang+, ICSICT'16]
- ▶ Randomly placing patterns according to certain constraints. (limited diversity)
- ▶ Generative machine learning models. (violating design rules) [Alec+, ICLR'16]

Preliminaries

Pattern Generation Challenges

- ▶ 7nm EUV metal layer unidirectional on-track shapes.
- ▶ Pitch, denoted as p , measures the distance between two adjacent tracks that contain shapes.
- ▶ T2T, denoted as t , measures the line-end-to-line-end distance between two adjacent shapes in a track.
- ▶ Wire length l and width w measure the shape size along and against the design track.



Evaluation of Pattern Library

All shape edges in a fixed-size window are aligned with x -axis and y -axis. If we extend all horizontal and vertical edges infinitely into scan lines, more non-overlapping scan lines always come with more complex patterns. We hence define the complexity of a layout pattern as follows.

- ▶ **Pattern Complexity.** The complexity of a pattern in x and y directions (denoted as c_x and c_y) are defined as the number of scan lines subtracted by one along x -axis and y -axis, respectively.

We also introduce the concept of *pattern diversity* (denoted as H) to measure how are the pattern complexities distributed in a given library. A larger H implies the library contains patterns that are more evenly distributed, as in the following definition.

- ▶ **Pattern Diversity.** The diversity of a pattern library is given by the *Shannon Entropy* of the pattern complexity sampled from the library,

$$H = - \sum_i \sum_j P(c_{xi}, c_{yj}) \log P(c_{xi}, c_{yj}),$$

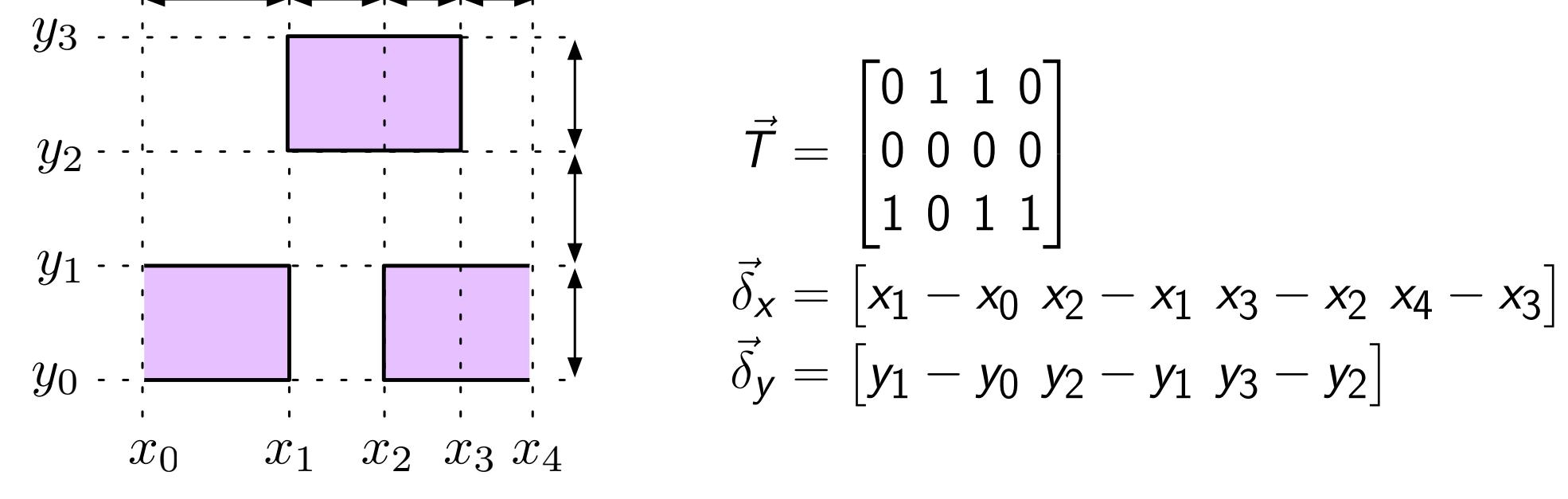
where $P(c_{xi}, c_{yj})$ is the probability of a pattern sampled from the library has complexities of c_{xi} and c_{yj} in x and y directions respectively.

Problem (Pattern Generation)

Given a set of layout design rules, the objective of pattern generation is to generate a pattern library such that the pattern diversity and the number of unique DRC-clean patterns in the library is maximized.

Methods

Squish Representation Example

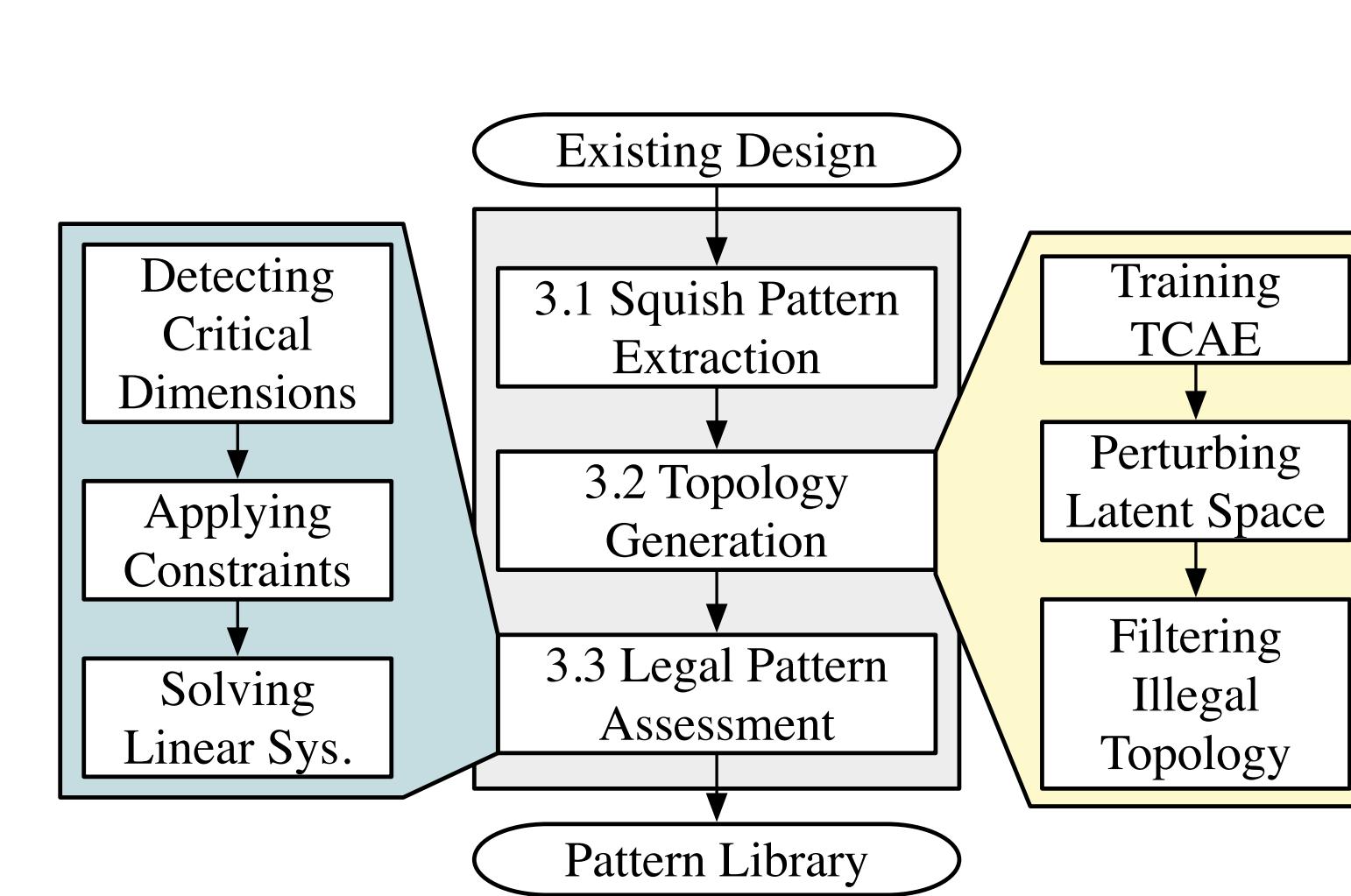


- ▶ Scan line-based representation, naturally supports easy computation of pattern complexity.
- ▶ Lossless feature representation.
- ▶ Easily feed into convolutional neural networks.

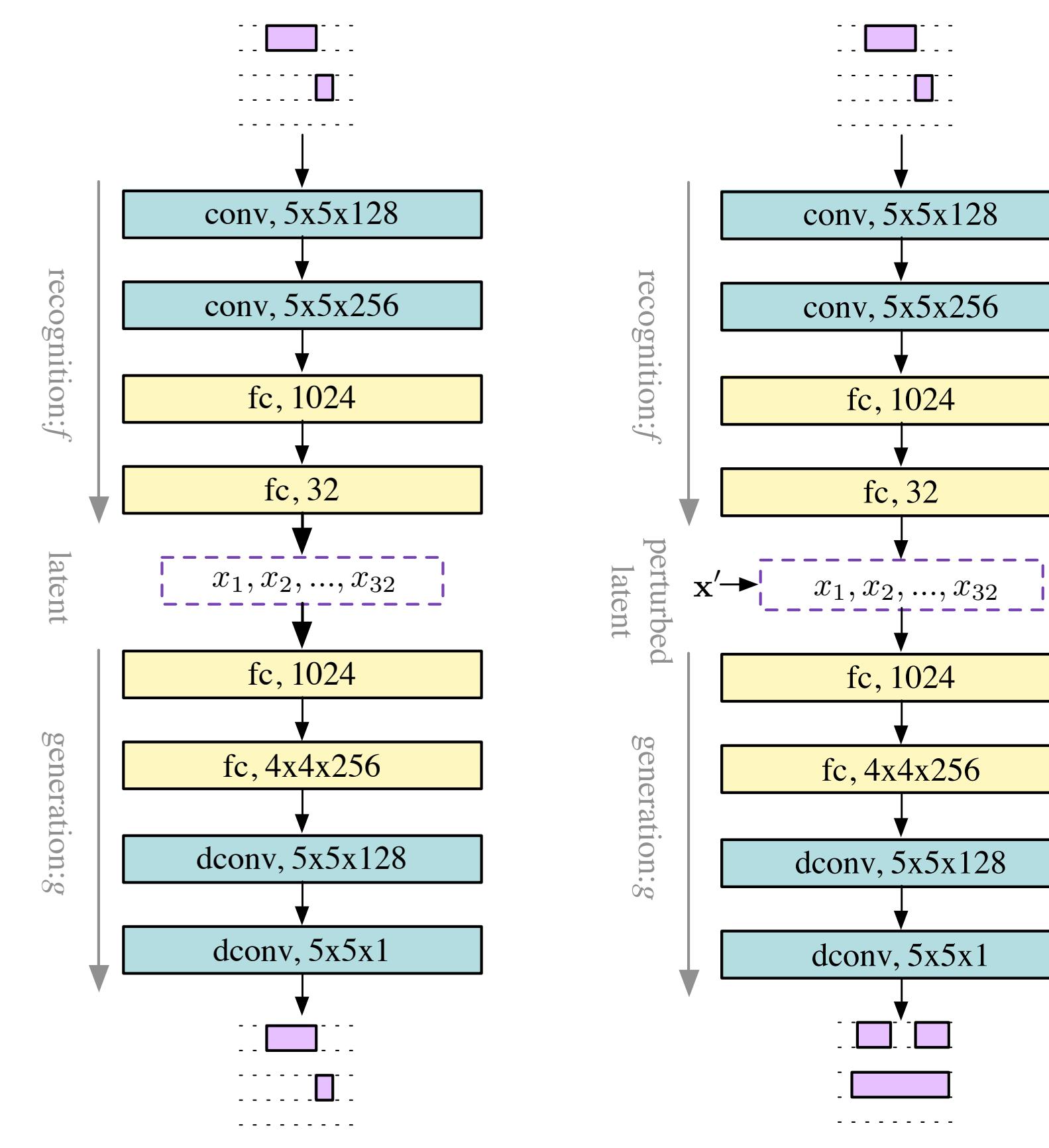
Problem Simplification

- ▶ Legal topology generation.
- ▶ Solving geometry constraints for DRC-clean patterns.

The Overall Flow



Transforming Convolutional Auto-Encoder



Perturbing the Latent Space

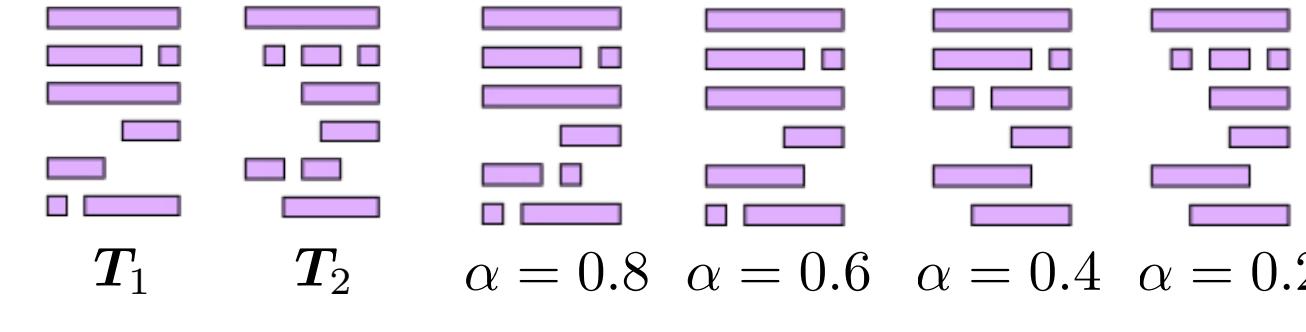
TCAE-Combine

- ▶ Generalization from existing topologies

$$\vec{T}_g = g(\sum_i \alpha_i f(\vec{T}_i)),$$

where $0 < \alpha_i < 1, \forall i$ are combination coefficients and satisfy $\sum_i \alpha_i = 1$.

- ▶ Sample results



Legal Pattern Assessment

Creating DRC constraints for legal δ_x s and δ_y s,

$$\begin{aligned} y_{i+1} - y_i &= \frac{p}{2}, \\ x_i - x_j &= t_{\min}, \\ x_i - x_j &= l_{\min}, \\ x_{i+1} - x_i &> 0, \\ x_{\max} - x_0 &= d_x, y_{\max} - y_0 = d_y. \end{aligned}$$

⋮

$\forall(i, j) \in \mathcal{C}_{T2T}$,

$\forall(i, j) \in \mathcal{C}_W$,

⋮

TCAE-Random

- ▶ Introducing perturbation from certain distribution randomly

$$\vec{T}_g = g(f(\vec{T}_i) + \Delta \vec{x}),$$

where $\Delta \vec{x} \sim \mathcal{N}$.

- ▶ **Feature Sensitivity.** Let $\vec{T} = [l_1 \ l_2 \ \dots \ l_n]^T$ be the output of the layer associated with the latent vector space. The sensitivity s_i of a latent vector node l_i is defined as the probability of reconstructed pattern being invalid when a perturbation $\Delta l_i \in [-t, t]$ is added up on l_i with everything else unchanged.

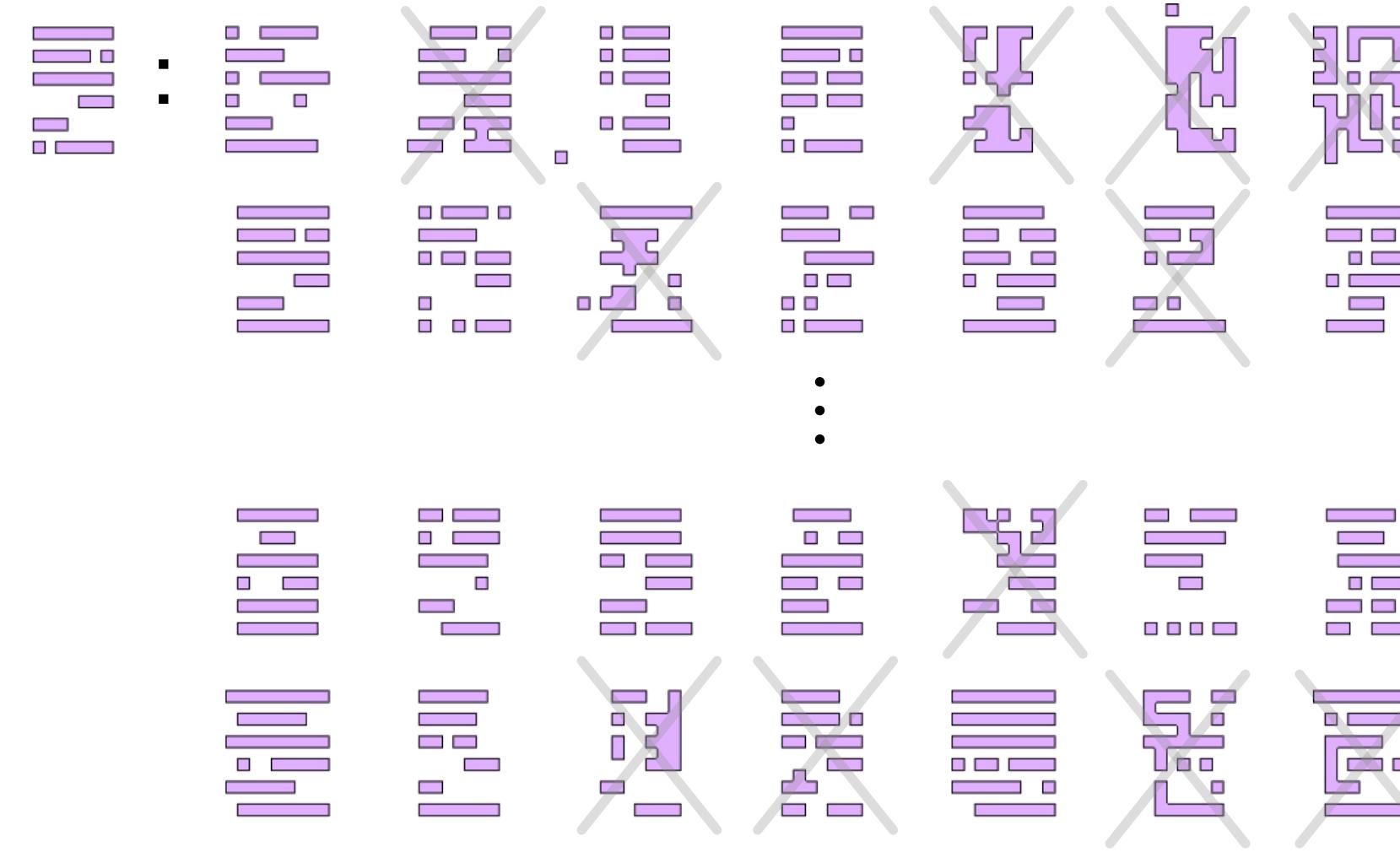
Results and Conclusion

Understanding Features in TCAE

Transformations	Reconstructed Topologies
Extend or pull back line-ends	
Create or destroy shapes	
Control shape directions	

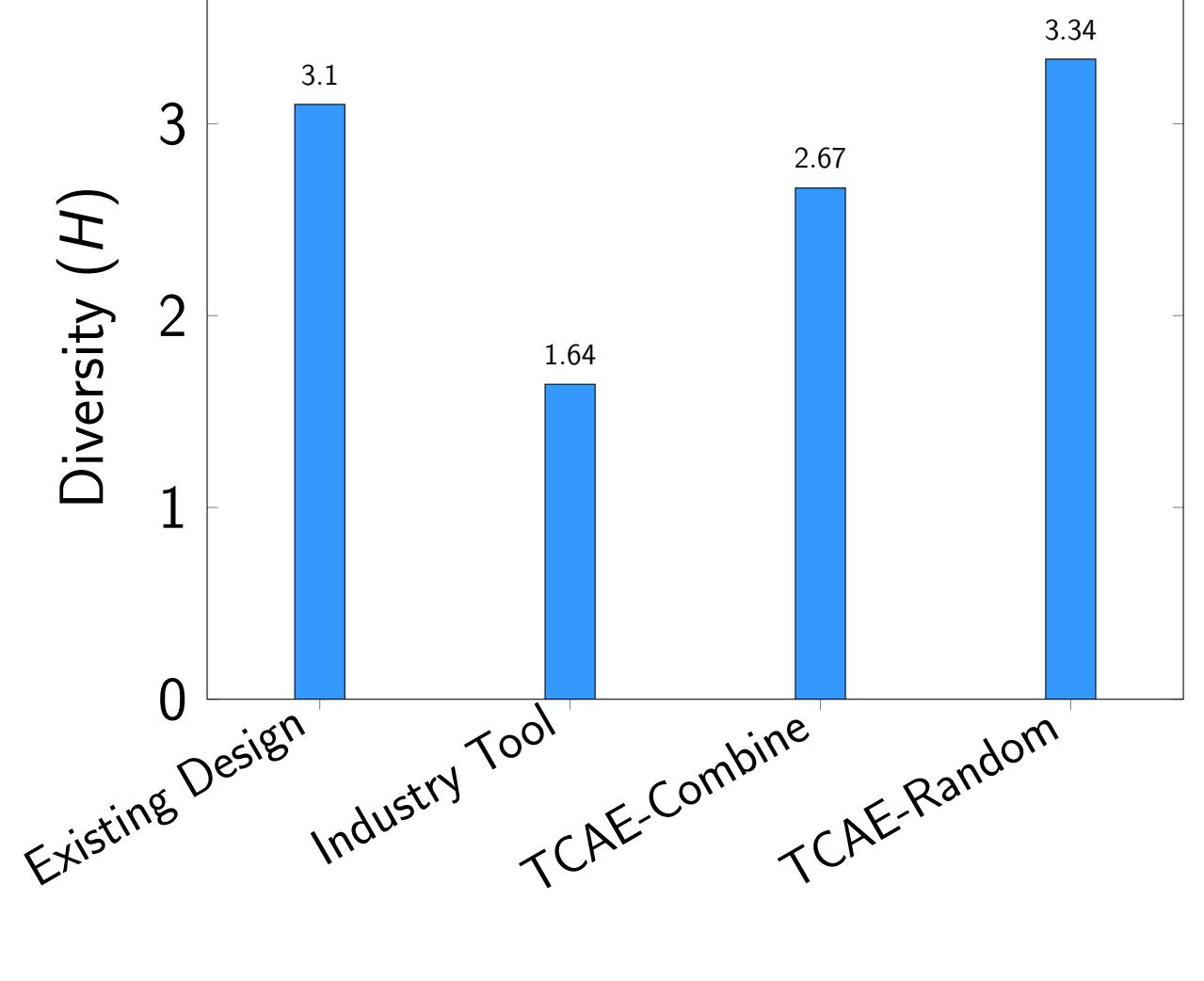
TCAE-Random

Origin



Comparison with State-of-the-Art

Perturbation with Gaussian exhibits greatest pattern generation power with around 30% generated patterns are unique and DRC clean.



Conclusion

- ▶ Address the pattern library requirements in DFM flows/researches under advanced technology nodes.
- ▶ Propose a TCAE framework that can capture layout design rule characteristics.
- ▶ We show auto-learned features contribute to layout space locally or globally.